

## Message Text

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ACTION EB-07

INFO OCT-01 CIAE-00 COME-00 DODE-00 NSAE-00 USIA-06  
TRSE-00 EUR-12 ERDA-05 ISO-00 ACDA-07 /038 W  
-----242019Z 021949 /63  
R 241405Z MAY 77  
FM USMISSION OECD PARIS  
TO SECSTATE WASH DC 6779

C O N F I D E N T I A L OECD PARIS 15229

EXCON

E.O. 11652: XGDS1  
TAGS: ESTC, COCOM, PL, US  
SUBJ: US SEMICONDUCTOR MANUFACTURING FACILITY TO POLAND  
IL-1355

REF: COCOM DOC. (77)309

1. ITALIAN AND GERMAN DELS RESERVED THEIR POSITION ON  
REFCASE AT COCOM MEETING 5/17 AS THEIR AUTHORITIES WERE  
STILL STUDYING THE CASE. UKDEL ALSO RESERVED AND ASKED  
THE FOLLOWING QUESTIONS WHICH WERE RECEIVED 5/23:
  - A. WHAT ASSURANCES COULD BE GIVEN THAT THE PRODUC-  
TION CAPACITY OF THE INSTALLATION WOULD BE LIM-  
ITED TO THE VOLUME MENTIONED IN PARAGRAPH 3 OF COCOM  
(77) 309?
  - B. WHAT PROPORTION OF SPARE OR STANDBY EQUIPMENT  
WAS INCLUDED IN THE DETAILED LIST IN ATTACHMENT 1?
  - C. HOW LONG DID THE US CONSIDER THE INSPECTION PRO-  
GRAM WOULD BE MAINTAINED AFTER THE FIRST TWO YEARS?
  - D. WHAT GROUND EXISTED FOR SUPPOSING THE EQUIPMENT  
UNDER DISCUSSION, OR POLISH-MADE COPIES OF IT,

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WOULD NOT BE USED FOR MAKING TTL OR ECL LARGE-SCALE  
INTEGRATED CIRCUITS, MICROWAVE AND ELECTRO-OPTIC  
DEVICES FOR MILITARY PURPOSES?

2. ACTION REQUESTED: INSTRUCTIONS FOR RESPONSE TO UK  
QUESTIONS.  
KATZ

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NNN

## Message Attributes

**Automatic Decaptioning:** X  
**Capture Date:** 01-Jan-1994 12:00:00 am  
**Channel Indicators:** n/a  
**Current Classification:** UNCLASSIFIED  
**Concepts:** ELECTRONIC EQUIPMENT, EXPORT CONTROLS  
**Control Number:** n/a  
**Copy:** SINGLE  
**Sent Date:** 24-May-1977 12:00:00 am  
**Decaption Date:** 01-Jan-1960 12:00:00 am  
**Decaption Note:**  
**Disposition Action:** RELEASED  
**Disposition Approved on Date:**  
**Disposition Case Number:** n/a  
**Disposition Comment:** 25 YEAR REVIEW  
**Disposition Date:** 22 May 2009  
**Disposition Event:**  
**Disposition History:** n/a  
**Disposition Reason:**  
**Disposition Remarks:**  
**Document Number:** 1977OECDP15229  
**Document Source:** CORE  
**Document Unique ID:** 00  
**Drafter:** n/a  
**Enclosure:** n/a  
**Executive Order:** X1  
**Errors:** N/A  
**Expiration:**  
**Film Number:** D770185-0381  
**Format:** TEL  
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**Handling Restrictions:** n/a  
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**Litigation Codes:**  
**Litigation History:**  
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**Message ID:** 40b7568b-c288-dd11-92da-001cc4696bcc  
**Office:** ACTION EB  
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**Original Handling Restrictions:** n/a  
**Original Previous Classification:** n/a  
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**Page Count:** 2  
**Previous Channel Indicators:** n/a  
**Previous Classification:** CONFIDENTIAL  
**Previous Handling Restrictions:** n/a  
**Reference:** n/a  
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**Review Action:** RELEASED, APPROVED  
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**Review Exemptions:** n/a  
**Review Media Identifier:**  
**Review Release Date:** n/a  
**Review Release Event:** n/a  
**Review Transfer Date:**  
**Review Withdrawn Fields:** n/a  
**SAS ID:** 2391246  
**Secure:** OPEN  
**Status:** NATIVE  
**Subject:** US SEMICONDUCTOR MANUFACTURING FACILITY TO POLAND IL-1355  
**TAGS:** ESTC, PL, US, COCOM  
**To:** STATE  
**Type:** TE  
**vdkgvwkey:** odbc://SAS/SAS.dbo.SAS\_Docs/40b7568b-c288-dd11-92da-001cc4696bcc  
**Review Markings:**  
Margaret P. Grafeld  
Declassified/Released  
US Department of State  
EO Systematic Review  
22 May 2009  
**Markings:** Margaret P. Grafeld Declassified/Released US Department of State EO Systematic Review 22 May 2009